



Pattern Recognition and Computer Vision Based on Deep Learning

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Message from the Guest Editors

Pattern recognition and computer vision are classic, exciting and fast-developing fields. They underpin developments in many fields, such as biometrics, bioinformatics, multimedia data analysis, smart city and, most recently, data science, and they have important theoretical and application value. Therefore, they have been a focus of text/speech/image/video-related processing and been the subject of a large amount of research. In recent years, deep learning technology has seen rapid development and made promising achievements in many fields. Especially in the fields of pattern recognition and computer vision, deep learning-based models have significantly improved algorithm performance. Therefore, it is particularly important to study pattern recognition and computer vision based on deep learning.

The purpose of this Special Issue is to present the latest advances of pattern recognition and computer vision technology based on deep learning and their applications in practice. We invite you to present high-quality research papers or literature reviews related to deep learning-based pattern recognition and computer vision.





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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